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10-3-01  
7/13

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Masamichi NAKASHIBA et al

Serial No. 09/589,388

Filed June 8, 2000



Docket No. 2000\_0722

Group Art Unit 3723

Examiner G. Nguyen

APPARATUS FOR AND METHOD FOR  
POLISHING WORKPIECE

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEE FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0976.

AMENDMENT

Assistant Commissioner for Patents,  
Washington, D.C.

Sir:

In response to the Office Action of June 21, 2001, please amend the above-referenced U.S. patent application as follows:

In the Claims:

Please add the following new claims:

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SEP 25 2001  
TECHNOLOGY CENTER R3700

for  
31  
73.(NEW) A polishing apparatus for polishing a surface of a workpiece,  
comprising:  
a top ring for holding a workpiece; and  
a plurality of chambers formed in said top ring, fluid pressures being  
supplied in said respective chambers to provide polishing pressure to a central area and  
an outer circumferential area of the workpiece, wherein a radial width of said outer  
circumferential area is narrower than that of said central area.

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